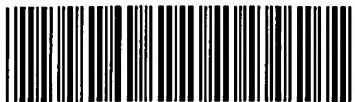


Search Notes**Application/Control No.**

10/603,310

Examiner

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Applicant(s)/Patent under Reexamination

STORZ, RAFAEL

Art Unit

2878

SEARCHED

Class	Subclass	Date	Examiner
250	201.3	7/21/2005	PMB
250	234	7/21/2005	PMB
250	235	7/22/2005	PMB
250	208.1	7/22/2005	PMB
250	306	7/25/2005	PMB
250	307	7/25/2005	PMB

**SEARCH NOTES
(INCLUDING SEARCH STRATEGY)**

	DATE	EXMR
((scan\$3 or scanning) adj3 (microscop\$6)) near5 ((parameter\$2) or (system near3 parameter\$2))	7/25/2005	PMB
((computer or process\$6)near6 (control\$6)near20(((scan\$3 or scanning)adj3(microscop\$6)) near5 ((parameter\$2)or(system)	7/25/2005	PMB
((computer or process\$6) near6 (control\$6)) near12 ((scan\$3 or scanning) adj3 (microscop\$6))	7/25/2005	PMB
((computer or process\$6)near6(control\$6))near10 (((scanning)or(microscop\$6))near5((parameter\$2) or (system near3 parameter\$2))	7/25/2005	PMB
((image or imaging) near3 (quality or feature\$2)) near6 (modify or modified or adjust\$6)	7/25/2005	PMB
(image\$2 or imaging) near6 (convert\$6 or conversion)	7/25/2005	PMB
((image\$2 or imaging) near6 (convert\$6 or conversion))near12(parameter\$2)	7/25/2005	PMB
Related patents	7/25/2005	PMB

INTERFERENCE SEARCHED

Class	Subclass	Date	Examiner